



## Traceability North America TC Chapter Meeting Summary and Minutes

Wednesday, July 28, 2021  
10:00 AM - 12:30 PM (Pacific Time)  
OVTCCM

### TC Chapter Announcements

*Next TC Chapter Meeting*

November 17, 2021

8:00 AM – 1:00 PM Pacific

OVTCCM

### Table 1 Meeting Attendees

*Italics indicate virtual participants*

**Co-Chairs:** Yaw Obeng (NIST), Dave Huntley (PDF Solutions)

**SEMI Staff:** Michelle Sun (SEMI)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
BESI	<i>Meusburger</i>	<i>Peter</i>	Samsung Austin	<i>Bruce</i>	<i>Eric</i>
Globalfoundries	<i>Hanan</i>	<i>Jeff</i>	SCREEN	<i>Nishimura</i>	<i>Takayuki</i>
IBM	<i>Begue</i>	<i>Christopher</i>	SEMI	<i>Sun</i>	<i>Michelle</i>
NIST	<i>Obeng</i>	<i>Yaw</i>	SUNY Poly	<i>Eisenbraun</i>	<i>Eric</i>
Omron	<i>Infelise</i>	<i>Nick</i>	Tokyo Electron	<i>Mashiro</i>	<i>Supika</i>
PDF Solutions	<i>Huntley</i>	<i>Dave</i>	Wolfsped Cree	<i>Barbieri</i>	<i>Tom</i>
PEER Group	<i>Fuchigami</i>	<i>Albert</i>			

### Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
None		

### Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None	

### Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6448A	New Standard – Specification for Equipment and Materials Labels	<b>Failed</b>
6698	Revision of SEMI M12-0706 (reapproved 0318), Specification for Serial Alphanumeric Marking of the Front Surface of Wafers, with title change to: Specification for Alphanumeric Marking of Wafers	<b>Failed</b>



**Table 4 Ballot Results**

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
6699	Revision of SEMI M13-0706 (reapproved 0318), Specification for Alphanumeric Marking of Silicon Wafers (Subject: adding alphanumeric marking at back surface in addition to front surface.)	<b>Failed</b>
6738	Reapproval of SEMI T16-0310 (Reapproved 0216) - Specification for Use of Data Matrix Symbolology for Automated Identification of Extreme Ultraviolet Lithography Masks	<b>Passed</b>
6739	Reapproval of SEMI T20-0710 (Reapproved 0416) - Specification for Authentication of Semiconductors and Related Products	<b>Passed</b>
6740	Reapproval of SEMI T8-1110 (Reapproved 0216) - Specification for Marking of Glass Flat Panel Display Substrates with a Two-Dimensional Matrix Code Symbol	<b>Passed</b>
6741	Reapproval of SEMI T9-1110 (Reapproved 0216) - Specification for Marking of Metal Lead-Frame Strips with a Two-Dimensional Data Matrix Code Symbol	<b>Passed</b>
6742	Reapproval of SEMI T7-0516 - Specification for Back Surface Marking of Double-Side Polished Wafers with a Two-Dimensional Matrix Code Symbol	<b>Passed</b>

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

**Table 5 Activities Approved by the GCS between meetings of the TC Chapter**

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

**Table 6 Authorized Activities**

Listing of all revised or new SNARF(s) approved by the Originating TC Chapter.

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

#1 SNARFs and TFOFs are available for review on the SEMI Web site at:

<http://downloads.semi.org/web/wstdsbal.nsf/TFOFSNARF>

**Table 7 Authorized Ballots**

<i>#</i>	<i>When</i>	<i>TF</i>	<i>Details</i>
6448B	Cycles 6, 7, or 8 of 2021	EMT TF	New Standard – Specification for Equipment and Materials Labels
6698A	Cycles 6, 7, or 8 of 2021	5-Year Review TF	Revision of SEMI M12-0706 (reapproved 0318), Specification for Serial Alphanumeric Marking of the Front Surface of Wafers, with title change to: Specification for Alphanumeric Marking of Wafers
6699A	Cycles 6, 7, or 8 of 2021	5-Year Review TF	Revision of SEMI M13-0706 (reapproved 0318), Specification for Alphanumeric Marking of Silicon Wafers (Subject: adding alphanumeric marking at back surface in addition to front surface.)
6604A	Cycles 6, 7, or 8 of 2021	5-Year Review TF	Line Item Revision to SEMI T5-1214: Specification for Alphanumeric Marking of Round Compound Semiconductor Wafers



**Table 8 SNARF(s) Granted a One-Year Extension**

#	TF	Title	Expiration Date
None			

**Table 9 SNARF(s) Abolished**

#	TF	Title
None		

**Table 10 Standard(s) to receive Inactive Status**

Standard Designation	Title
None	

**Table 11 New Action Items**

Item #	Assigned to	Details
None		

**Table 12 Previous Meeting Action Items**

Item #	Assigned to	Details
None		

**1 Welcome, Reminders, and Introductions**

Yaw Obeng (NIST) called the meeting to order at 10:05. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

**Attachment:** Required Element Nov 2020 Rev1

**2 Review of Previous Meeting Minutes**

The TC Chapter reviewed the minutes of the previous meeting.

- Motion:** Approve the minutes as written
- By / 2<sup>nd</sup>:** By: Nick Infelise / Omron Electronics, Inc  
Second: Albert Fuchigami / PEER Group Inc.
- Discussion:** None
- Vote:** 6-Y 0-N. Motion passed.

**Attachment:** NA\_Traceability-Minutes-Apr-2021

**3 Liaison Reports**

*3.1 SEMI Staff Report*

Michelle Sun (SEMI) gave the SEMI Staff Report. Of note:

SEMI Global Calendar of Events

- SEMICON China (March 17-19, 2021; Shanghai, China)



- SEMICON Southeast Asia (May 18-20, 2021; Penang, Malaysia)
- SEMICON Taiwan (Sept 8-10, 2021; Taipei, Taiwan)
- SEMICON West (December 7-9, 2021; [Hybrid] San Francisco, CA)

Critical Dates for SEMI Standards Ballots

- Cycle 2-2021: Ballot Submission Due: Jan 29/Voting Period: Feb 10 – Mar 12
- Cycle 3-2021: Ballot Submission Due: Mar 9/Voting Period: Mar 23 – Apr 22
- Cycle 4-2021: Ballot Submission Due: Apr 14/Voting Period: Apr 28 – May 28
- Cycle 5-2021: Ballot Submission Due: May 18/Voting Period: June 1 – July 1
- Cycle 6-2021: Ballot Submission Due: Aug 3/Voting Period: Aug 17 – Sept 16
- Cycle 7-2021: Ballot Submission Due: Sept 1/Voting Period: Sept 15 – Oct 15
- Cycle 8-2021: Ballot Submission Due: Oct 8/Voting Period: Oct 22 – Nov 22
- Cycle 9-2021: Ballot Submission Due: Nov 16/Voting Period: Nov 30 – Dec 30

Critical Dates: <http://www.semi.org/en/Standards/Ballots>

Standards Publications Report

Total in portfolio – 1,029 (includes 274 Inactive Standards)

<i>Cycle</i>	<i>New</i>	<i>Revised</i>	<i>Reapproved</i>	<i>Withdrawn</i>
November 2020	1	2	0	0
December 2020	1	3	3	0
January 2020	0	1	6	0

New Standards

<i>Cycle</i>	<i>Designation</i>	<i>Title</i>	<i>Committee</i>	<i>Region</i>
November 2020	SEMI C100	Guide for Reporting Chemical Mechanical Planarization (CMP) Polishing Pads Hardness Used in Semiconductor Manufacturing	Liquid Chemicals	NA
December	SEMI PV97	Specification for Silicon Powder Used in Polysilicon Production	Photovoltaic	CH

Inactive Standards

*Number of Inactive Standards*

Assembly & Packaging	48
Automated Test Equipment	2
Compound Semiconductor Materials	4
Environmental Health & Safety	8
Facilities	15
FPD – Equipment	5
FPD – Factory Automation	14
FPD – Materials & Components	13
Gases	18
Information & Control	37
Liquid Chemicals	26
MEMS	3
Metrics	12
Micropatterning	30
Photovoltaic	1
Physical Interfaces & Carriers	19
Silicon Wafer	11

## Regulations &amp; Procedure Manual

- Regulations ((November 5, 2020)
  - Clarification on § 6.5, Disbandment of a TC Chapter
  - Requires an RSC to disband a TC Chapter when it is shown to be inactive by failing to:
    - hold meetings for two consecutive years,
    - report activity to its RSC for two consecutive years, or
    - initiate new Standards Documents activities.
  - Procedure Manual (November 5, 2020)
  - New § 6.1.3.4.1 defining detailed procedures for disbandment of inactive TC Chapters.

Official Virtual TC Chapter Meeting Rooms *{See attachment for additional slides}*

- All Chapters of the PIC GTC have completed the simulation training of an Official Virtual TC Chapter Meeting (OVTCCM).
- Nonconforming Titles (See PM Appendix 4) *{None}*
- SNARF 3 Year Status, TC Chapter may grant a one-year extension *{None}*
- Five-Year Review *{None}*

**Attachment:** Staff Report July 2021\_v1 - Traceability

#### 4 Ballot Review

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

##### 4.1 Document 6448A, New Standard – Specification for Equipment and Materials Labels

**Motion:** To incorporate the technical change(s).

**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Supika Mashiro / Tokyo Electron Ltd.

**Discussion:** Change is too significant for approval through Ratification Ballot

**Vote:** 2-Y 2-N. Motion failed.

**Motion:** This Document failed TC Chapter review and will be returned to the TF for rework.

**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Supika Mashiro / Tokyo Electron Ltd.

**Discussion:** We've voted on this Standard twice with >90% approval rate. We would ask that Reject voters participate in EMT meeting prior to TC Meeting during the next time around.

**Vote:** 4-Y 0-N. Motion passed.



4.2 Document 6698, Revision of SEMI M12-0706 (reapproved 0318), Specification for Serial Alphanumeric Marking of the Front Surface of Wafers, with title change to: Specification for Alphanumeric Marking of Wafers

**Motion:** Nakai, Tetsuya (SUMCO), Negative 1: Negative is related and persuasive. (Needs > 1/3 votes to pass.)  
**By / 2<sup>nd</sup>:** By: Nick Infelise / Omron Electronics, Inc  
Second: Albert Fuchigami / PEER Group Inc.  
**Discussion:** None  
**Vote:** 7-Y 0-N. Motion passed.

**Motion:** This Document failed TC Chapter review and will be returned to the TF for rework.  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Nick Infelise / Omron Electronics, Inc  
**Discussion:** None  
**Vote:** 7-Y 0-N. Motion passed.

4.3 Document 6699, Revision of SEMI M13-0706 (reapproved 0318), Specification for Alphanumeric Marking of Silicon Wafers (Subject: adding alphanumeric marking at back surface in addition to front surface.)

**Motion:** Nakai, Tetsuya (SUMCO), Negative 1: Negative is related and persuasive. (Needs > 1/3 votes to pass.)  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Nick Infelise / Omron Electronics, Inc  
**Discussion:** None  
**Vote:** 8-Y 0-N. Motion passed.

**Motion:** This Document failed TC Chapter review and will be returned to the TF for rework.  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Nick Infelise / Omron Electronics, Inc  
**Discussion:** None  
**Vote:** 6-Y 0-N. Motion passed.

4.4 Document 6738, Reapproval of SEMI T16-0310 (Reapproved 0216) - Specification for Use of Data Matrix Symbolology for Automated Identification of Extreme Ultraviolet Lithography Masks

**Motion:** This is not a Safety Document, when all safety-related information is removed, the Document is still technically sound and complete. (Regulations ¶ 8.7.1)  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Tom Barbieri / Cree, Inc.  
**Discussion:** None  
**Vote:** 3-Y 0-N. Motion passed.

**Motion:** This Document passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.  
**Discussion:** None  
**Vote:** 3-Y 0-N. Motion passed.



**Attachment:** Ballot Report - 6738

4.5 Document 6739, Reapproval of SEMI T20-0710 (Reapproved 0416) - Specification for Authentication of Semiconductors and Related Products

**Motion:** This is not a Safety Document, when all safety-related information is removed, the Document is still technically sound and complete. (Regulations ¶ 8.7.1)  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.  
**Discussion:** None  
**Vote:** 4-Y 0-N. Motion passed.

**Motion:** This Document passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.  
**Discussion:** None  
**Vote:** 3-Y 0-N. Motion passed.

**Attachment:** Ballot Report – 6739

4.6 Document 6740, Reapproval of SEMI T8-1110 (Reapproved 0216) - Specification for Marking of Glass Flat Panel Display Substrates with a Two-Dimensional Matrix Code Symbol

**Motion:** This is not a Safety Document, when all safety-related information is removed, the Document is still technically sound and complete. (Regulations ¶ 8.7.1)  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.  
**Discussion:** None  
**Vote:** 2-Y 0-N. Motion passed.

**Motion:** This Document passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.  
**Discussion:** None  
**Vote:** 2-Y 0-N. Motion passed.

**Attachment:** Ballot Report - 6740

4.7 Document 6741, Reapproval of SEMI T9-1110 (Reapproved 0216) - Specification for Marking of Metal Lead-Frame Strips with a Two-Dimensional Data Matrix Code Symbol

**Motion:** This is not a Safety Document, when all safety-related information is removed, the Document is still technically sound and complete. (Regulations ¶ 8.7.1)  
**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.  
**Discussion:** None



**Vote:** 2-Y 0-N. Motion passed.

**Motion:** This Document passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.

**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.

**Discussion:** None

**Vote:** 2-Y 0-N. Motion passed.

**Attachment:** Ballot Report - 6741

#### 4.8 Document 6742, Reapproval of SEMI T7-0516 - Specification for Back Surface Marking of Double-Side Polished Wafers with a Two-Dimensional Matrix Code Symbol

**Motion:** This is not a Safety Document, when all safety-related information is removed, the Document is still technically sound and complete. (Regulations ¶ 8.7.1)

**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.

**Discussion:** None

**Vote:** 2-Y 0-N. Motion passed.

**Motion:** This Document passed TC Chapter review as balloted and will be forwarded to the ISC A&R SC for procedural review.

**By / 2<sup>nd</sup>:** By: Albert Fuchigami / PEER Group Inc.  
Second: Takayuki Nishimura / SCREEN Semiconductor Solution Co., Ltd.

**Discussion:** None

**Vote:** 2-Y 0-N. Motion passed.

**Attachment:** Ballot Report - 6742

## 5 Subcommittee and Task Force Reports

### 5.1 *Single Device Traceability (SDT) Task Force*

- Liaison Requests
  - Liaison with GSA-TIES (Type I) was approved. Development of Doc 6504 with GSA-TIES is ongoing.
  - Liaison with IPC (Type II): Nonvoting ISC Chair approved request on 8/18/2021. Currently working with IPC on development of Memorandum of Understanding (MOU).
  - Liaison with ISO 292 (Type III): Liaison request was edited per ISC feedback. Request has been submitted to ISC again for voting.

## 6 Next Meeting and Adjournment

The next meeting is scheduled for November 17, 2021, from 8:00 AM – 1:00 via Web Conference. See <http://www.semi.org/standards-events> for the current list of events.

Adjournment: 12:41.





Respectfully submitted by:

Michelle Sun

Coordinator

SEMI North America

Phone: 408.943.7982

Email: [msun@semi.org](mailto:msun@semi.org)

Minutes tentatively approved by:

Dave Huntley (PDF Solutions), Co-chair	8/30/2021
Yaw Obeng (NIST), Co-chair	8/30/2021

**Table 13 Index of Available Attachments<sup>#1</sup>**

<i>Title</i>	<i>Title</i>
Required Element Nov 2020 Rev1	Ballot Report - 6740
NA_Traceability-Minutes-Apr-2021	Ballot Report - 6741
Ballot Report - 6738	Ballot Report - 6742
Ballot Report – 6739	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at [www.semi.org](http://www.semi.org). For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.